Annual Report of an ANSI/OEOSC TAG to ISO TC172 Subcommittee Covering the Year 2014

TAG Subcommittee Number and Name:

SC3 Optical Materials and Components

TAG Subcommittee Leader:

Leonard Hanssen

ISO Meetings Held During 2014

Subcommittee meetings usually include break-out meetings of working groups and project groups. List the top-level meeting; do not list the break-out meetings.

Subcommittee, Working, or Project Group Meeting Name	Date(s)	Location
No meetings were held in 2014		

ISO Meetings Scheduled for 2015

Subcommittee meetings usually include break-out meetings of working groups and project groups. List the top-level meeting; do not list the break-out meetings.

Subcommittee, Working, or Project Group Meeting Name	Date(s)	Location
None scheduled at this time. However, since three new projects have very recently been approved, we expect the SC3 Chair to organize a meeting this year. One possibility would be a joint meeting with SC1 in France in the October/November time frame.	Potential: October/November	Potential: Paris, France

Significant Accomplishments in 2014

ISO Subcommittee

Mr. Tatsuro Otaki (Japan) was confirmed as the new chair of SC3. Conveners were reappointed for WG1 and WG3 and a new convener for WG2. Two new ISO Standards were published: ISO 17328:2014 (Ed. 1) Optics and photonics -- Optical materials and components – *Test method for refractive index of infrared optical materials*; and ISO 17411:2014 (Ed. 1) Optics and photonics -- Optical materials and components – *Test method for homogeneity of optical glasses by laser interferometry.* Three new projects were approved for work at the end of the year.

US TAG Subcommittee

Mr. Trey Turner was confirmed as the new convener for WG2. Dr. Leonard Hanssen was confirmed as the new TAG leader for SC3.

Significant Problems Encountered in 2014

ISO Subcommittee

For 2014, the main problem was a lack of activity, resulting in no meetings taking place. The last meeting of SC3 was in 2011 in Okinawa, Japan. Four test methods were proposed during the year: three methods for the measurement of homogeneity, striae, and impurities, respectively, of infrared optical materials and components were proposed by the Chinese delegation, as well as one on the spectral measurement of scatter from infrared optical components by the Japanese delegation. Initially, all four were not approved due to an insufficient number of members willing to participate (2 and 3; minimum of 4). However, later in the year, around the time of the SC1 meeting in Berlin in September, where this topic was discussed amongst the participants, revised versions of the first three methods were submitted by China and later approved, with seven members agreeing to participate in the projects: ISO/AWI 19740 Optics and photonics -- Optical materials and components -- *Test method for homogeneity of infrared optical materials*; ISO/AWI 19741 Optics and photonics -- Optical materials and components -- *Test method for striae of infrared optical materials*; and ISO/AWI 19741 Optics and photonics -- Optical materials and components -- *Test method for impurities of infrared optical materials.*

US TAG Subcommittee

No additional news.

Projections for 2015

ISO Subcommittee

Goal: actively participate in the development of the new test method projects.

TAG Subcommittee

Goal: obtain industry input and contributions to the three new NWIPs on infrared optical materials and components.